

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of:

Takaei SASAKI et al

Confirmation No.:

Serial No.: New Application

Filed: November 14, 2003

For: METHOD AND APPARATUS FOR DRY-ETCHING HALF-TONE  
PHASE-SHIFT FILMS, HALF-TONE PHASE-SHIFT PHOTOMASKS  
AND METHOD FOR THE PREPARATION THEREOF, AND  
SEMICONDUCTOR CIRCUITS AND METHOD FOR THE  
FABRICATION THEREOF

**PRELIMINARY AMENDMENT**

Commissioner for Patents  
P.O. Box 1450  
Alexandria, Virginia 22313-1450

November 14, 2003

Sir:

Prior to calculation of the filing fees and examination on the merits, please  
amend the above-identified application as follows: